

PATENT/OFFICIAL

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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Technology Center 2100

In re Application of

Horne L. KOH

Serial No. 09/928,473

: Group Art Unit: 2812

Filed: August 14, 2001

: Examiner:

For: TOOL SERVICES LAYER FOR PROVIDING TOOL SERVICE FUNCTIONS IN CONJUNCTION WITH TOOL FUNCTIONS

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents  
Alexandria, VA 22313-1450

**Sir:**

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right

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to present to the Office the relevant facts and law regarding the appropriate status of such document.

No certification or fee is believed to be required. However, the Commissioner is hereby authorized to charge any additional fees should any be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

HALE AND DORR LLP

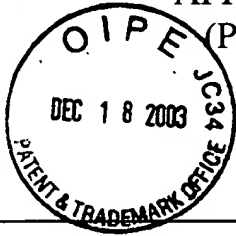
A handwritten signature in black ink, appearing to read "Scott M. Alter", written over the printed name.

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**INFORMATION DISCLOSURE  
CITATION IN AN  
APPLICATION**  
(PTO-1449)



ATTY. DOCKET NO.  
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USA/Consilium/Consilium

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09/928,473

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APPLICANT  
Horne L. KOH

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FILING DATE  
August 14, 2001

GROUP  
2812

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						Yes	No
	WO 01/11679	02/15/01	WIPO			X	
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	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 – 805.
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	2000. "Microsense II Capacitance Gaging System." <a href="http://www.adetech.com">www.adetech.com</a> .

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)</b> 				ATTY. DOCKET NO. 005123 USA/Consilium/Consilium		SERIAL NO. 09/928 473 <b>RECEIVED</b> DEC 22 2003 Technology Center 2100	
				APPLICANT Horne L. KOH			
				FILING DATE August 14, 2001		GROUP 2812	
<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
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